

## EAST Search History

## EAST Search History (Prior Art)

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S1	18	("20020132051"   "20030180571"   "4405660"   "5277939"   "5958204"   "6153313"   "6312832"   "6737110").PN.	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2008/09/30 15:46
S2	1	((MARION) near2 (BARTSCH)).INV.	US-PGPUB; USPAT	OR	ON	2008/09/30 15:58
S3	1	((MARION) near2 (BARTSCH)).INV.	EPO; JPO; DERWENT	OR	ON	2008/09/30 15:58
S4	1	((BERND) near2 (BAUFELD)).INV.	US-PGPUB; USPAT	OR	ON	2008/09/30 15:58
S5	1	((BERND) near2 (BAUFELD)).INV.	EPO; JPO; DERWENT	OR	ON	2008/09/30 15:58
S6	2	S2 S3 S4 S5	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2008/09/30 16:05
S7	7	428/469.ccls. and (((thick thickness) with micron with ceramic) same (metal metallic)). ti,ab,clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2008/09/30 16:29
S8	10	428/701,702.ccls. and (((thick thickness) with micron with ceramic) same (metal metallic)). ti,ab,clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2008/09/30 17:01
S9	7	S8 NOT S7	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2008/09/30 17:01
S10	32	428/469.ccls. and (aluminum with substrate) and ((thick thickness) with micron with (ceramic oxide)). ti,ab,clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2008/09/30 18:03

S11	19	S10 and ((EBPVD EB-PVD PVD (electron near3 beam)) (APS (air near3 plasma)) (CVD (chemical near3 vapor)))	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2008/09/30 18:09
S12	13	S10 not S11	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2008/09/30 18:09
S13	41	(micron micrometer) with (zirconia YSZ) with thick\$ with (TBC topcoat)	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2009/08/29 16:08
S14	6	((electron with beam with vapor) EB-PVD EBPVD APS (air with plasma with spray)) and ((chemical with vapor with deposition) CVD (electrophoresis with sinter\$) (dip near3 coat) dip-coat\$ dipcoat\$) and S13	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2009/08/29 16:11
S15	50	(micron micrometer) with (zirconia YSZ) with thick\$ with (thermal with barrier)	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2009/08/29 16:41
S16	23	((electron with beam with vapor) EB-PVD EBPVD APS (air with plasma with spray)) and ((chemical with vapor with deposition) CVD (electrophoresis with sinter\$) (dip near3 coat) dip-coat\$ dipcoat\$) and S15	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2009/08/29 16:41
S17	3	((((electron with beam with vapor) EB-PVD EBPVD) and ((chemical with vapor with deposition) CVD (electrophoresis with sinter\$) (dip near3 coat) dip-coat\$ dipcoat\$)) with (zirconia YSZ (stabilized near4 zirconium)) with (TBC topcoat)	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2009/08/29 17:38

S18	48	((electron with beam with vapor) EB-PVD EBPVD) and ((chemical with vapor with deposition) CVD (electrophoresis with sinter\$) (dip near3 coat) dip-coat\$ dipcoat \$)) with (zirconia YSZ (stabilized near4 zirconium))	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2009/08/29 17:41
S19	2	((electron with beam with vapor) EB-PVD EBPVD) and ((chemical with vapor with deposition) CVD (electrophoresis with sinter\$) (dip near3 coat) dip-coat\$ dipcoat \$)) with (zirconia YSZ (stabilized near4 zirconium)) with (thermal with barrier)	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2009/08/29 17:42

8/29/2009 10:23:12 PM

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